

0.6 μ m CMOS Process

Standard Features

- ❖ Single or double poly
- ❖ Double metal
- ❖ 5.5V max operating voltage
- ❖ Twin well

Process Technology

- ❖ 5X Stepper
- ❖ EPI starting material provides latch-up protection
- ❖ Double well implant
- ❖ Ldd for hot electron reliability
- ❖ Sandwich metal for e-m
- ❖ Titanium nitride barrier metal

Standard Layout Rules and Process Parameters

	Values	Units
Min gate length (N&P)	0.6	μ m
Gate oxide	130	Å
Inter-poly dielectric (oxide equiv.)	525	Å
Active (width/space)	0.6/1.0	μ m
Poly 1 (width/space)	0.6/0.7	μ m
	(Cap Bottom Plate)	
Poly 2 (width/space)	0.6/0.7	μ m
	(CMOS Gate and Cap Top Plate)	
Contact (width/space)	0.6/0.6	μ m
Via (width/space)	0.6/0.8	μ m
Metal 1 (width/space)	0.8/0.8	μ m
Metal 2 (width/space)	0.8/0.9	μ m

Typical Electrical Parameters

	N-CH	P-CH	Units
Vt(30X0.8 μ m)	0.92	-0.85	V
Ids	0.51	-0.27	mA/ μ m
Gain μ C (30X30)	110	38	μ A/V ²
Body Effect	0.45	0.32	V ^{1/2}
Sub-threshold slope	90	90	mV/decade
Leff	0.48	0.6	μ m
Xj	0.27	0.21	μ m
Rs	39	100	Ω /square
Rs poly	—	24	Ω /square